

Construction of the Belle II Pixel-Vertex Detector

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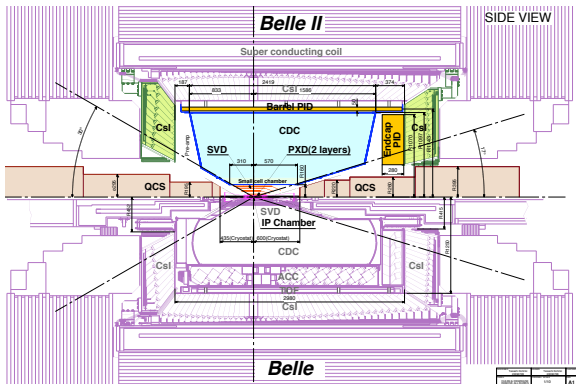
DEPFET



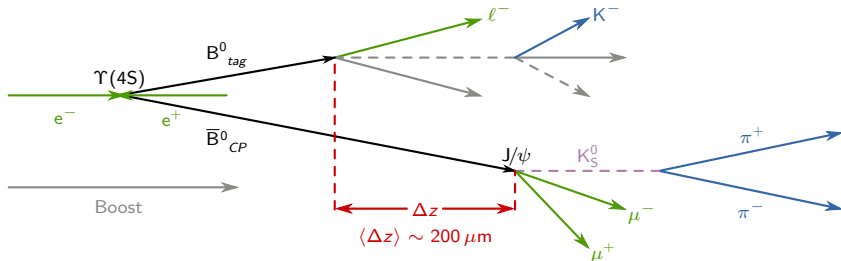
Belle/Belle II Experiment
Pixel Vertex Detector
PXD Overview
Mechanical Tests
Conclusions

Belle/Belle II Experiment

- ▶ asymmetric e^+e^- experiment mainly at the $\Upsilon(4S)$ resonance (10.58 GeV)
- ▶ KEKB peak luminosity of $2.11 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$ (world record)
- ▶ 1023 fb^{-1} integrated luminosity since 1999 (772 million $B\bar{B}$ pairs)
- ▶ upgrade to SuperKEKB/Belle II 2010-2013
(target luminosity: $8 \times 10^{35} \text{ cm}^{-2}\text{s}^{-1}$)



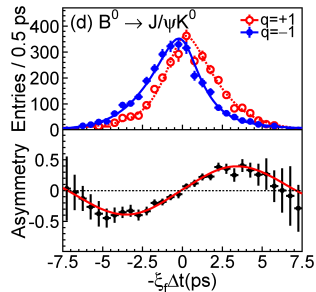
Vertex finding



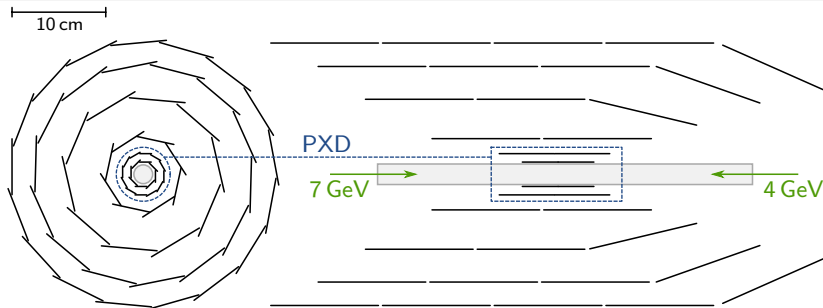
Vertex finding is the Key to CP-Violation measurement:

- ▶ CP violation is time dependent ($\langle \Delta t \rangle \sim 1 \text{ ps}$)
- ▶ boost translates lifetime difference into vertex distance ($\langle \Delta z \rangle \sim 200 \mu\text{m}$)

➡ precise silicon vertex detector needed



Belle II Vertex Detector



Will consist of two **mechanically independent** subdetectors:

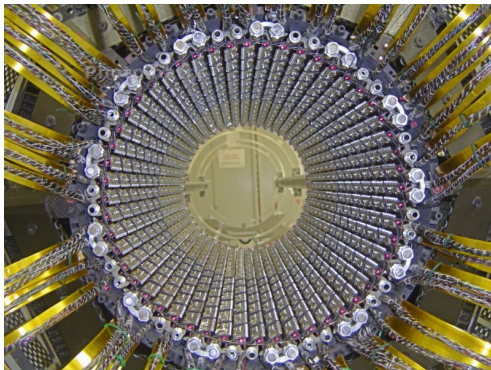
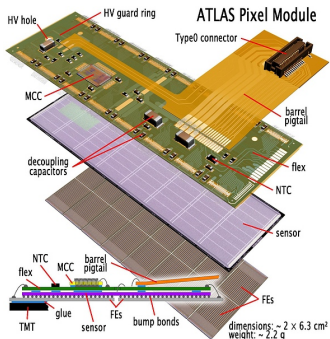
Pixel Vertex Detector

- ▶ two layer DEPFET pixel detector
- ▶ very low material budget (0.14% X_0 per layer)
- ▶ mounted on beampipe
- ▶ 40 sensor modules

Strip Vertex Detector

- ▶ four layer double sided strip detector
- ▶ forward parts will be slanted
- ▶ attached to CDC
- ▶ 187 sensor modules

Standard Silicon Detector



- ▶ multiple sensitive modules are glued on support ribs which provide mechanical stability
- ▶ support, cooling and cables inside acceptance region
- ➔ too much material for Belle (10 GeV CM energy)

PXD Mechanical Design

Vertex resolution is the key to CP-Violation

➡ low material budget required to minimize energy loss and multiple scattering, leading to a different design compared with existing Silicon detectors

- ▶ silicon sensors self supporting
- ▶ sensitive area will be thinned down to $75\ \mu\text{m}$
- ▶ almost no additional material inside of the acceptance

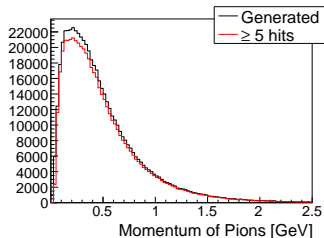
Silicon has good mechanical properties (high tensile strength, no plastic deformation, good elasticity)

But:

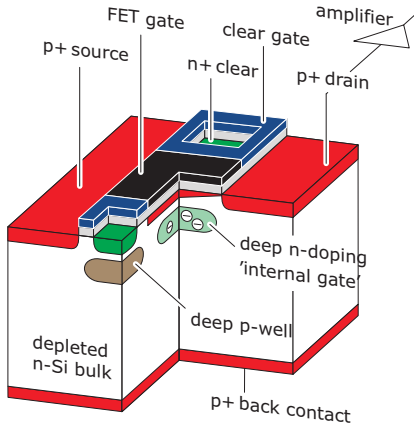
Silicon is very brittle: Once there is a small crack, this crack can grow very easily

No prior experience with this design

➡ additional tests required to make sure nothing breaks



DEPFET Pixel Detector



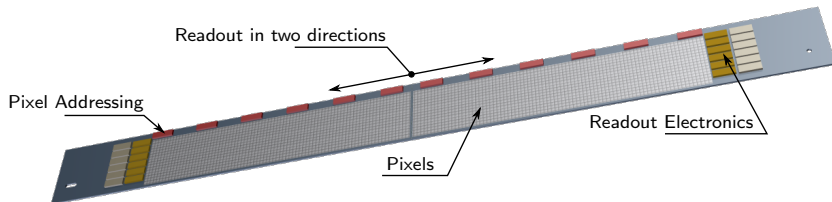
The DEPFET Principle

- ▶ FE-Transistor on each pixel
- ▶ doped areas beneath transistor form electron trap
- ▶ traversing charged particles produces electron hole pairs
- ▶ electrons get trapped and act as gate
- ▶ integrating device, always active
- ▶ collected charge has to be cleared after readout

➔ low noise, fast signal collection, low power consumption

Additional talks on DEPFET on Thursday by Christian Koffmane and Andreas Ritter

Pixel Sensor



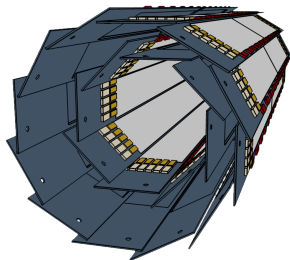
A sensor consists of many pixels in a 2D grid on a silicon module

- ▶ some additional electronics needed for addressing and readout of the pixels
- ▶ pixels are read out to both sides: one side per half

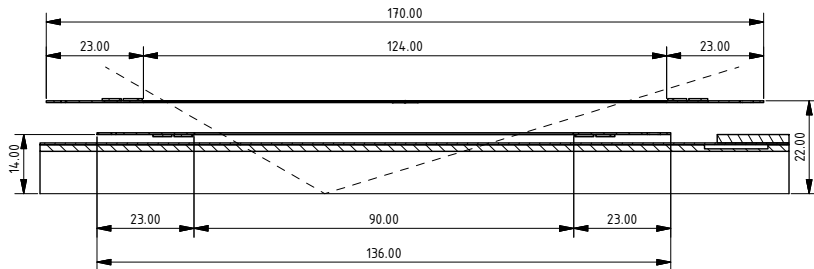
Sensor has to be cooled

- ▶ active area produces 0.5 W of heat
- ▶ addressing chips produce 0.5 W of heat
- ▶ readout electronics produce 8 W of heat per side

Layout of the PXD

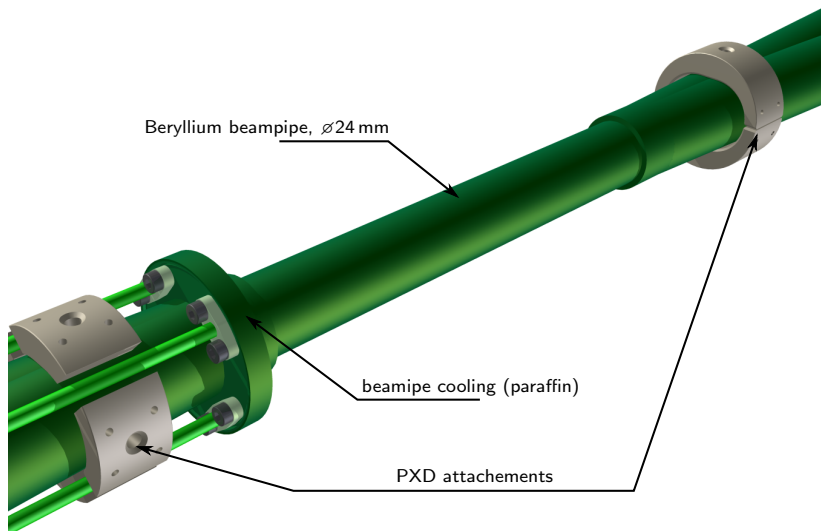


- ▶ PXD consists of 20 Modules in 2 layers
- ▶ each module has 1600×250 pixels (8 M pixel in total)
- ▶ pixel size of $50 \times 50 \mu\text{m}$ for the inner layer and $75 \times 50 \mu\text{m}$ in the outer layer
- ▶ each pixel readout with 8bit ADC
- ▶ total readout time of $20 \mu\text{s}$



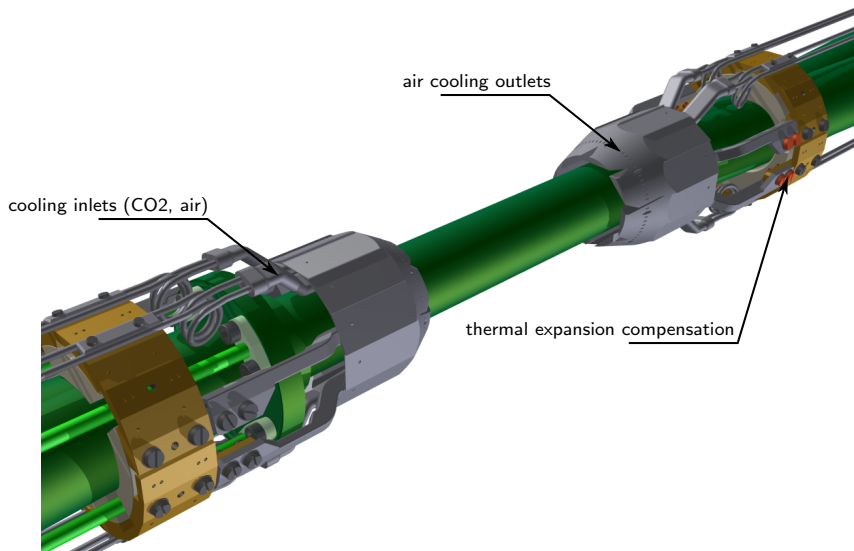
PXD Support

Beampipe including PXD Attachments



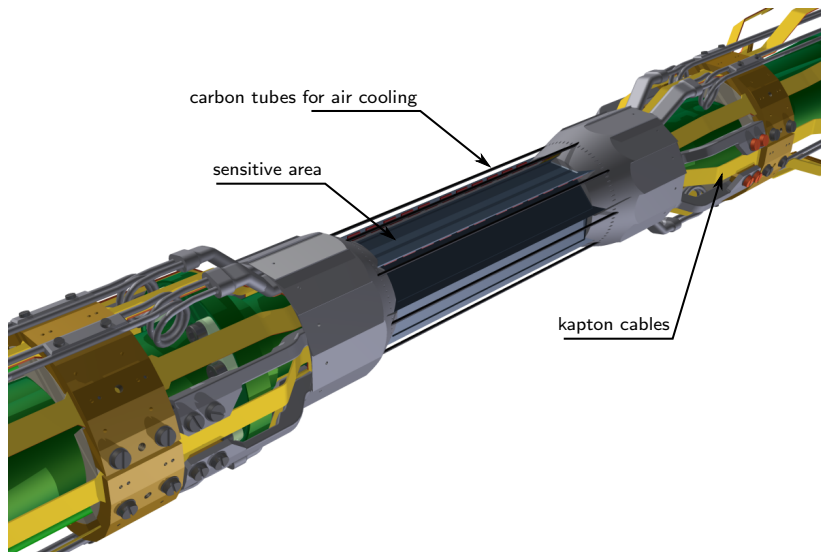
PXD Support

Mechanical Support



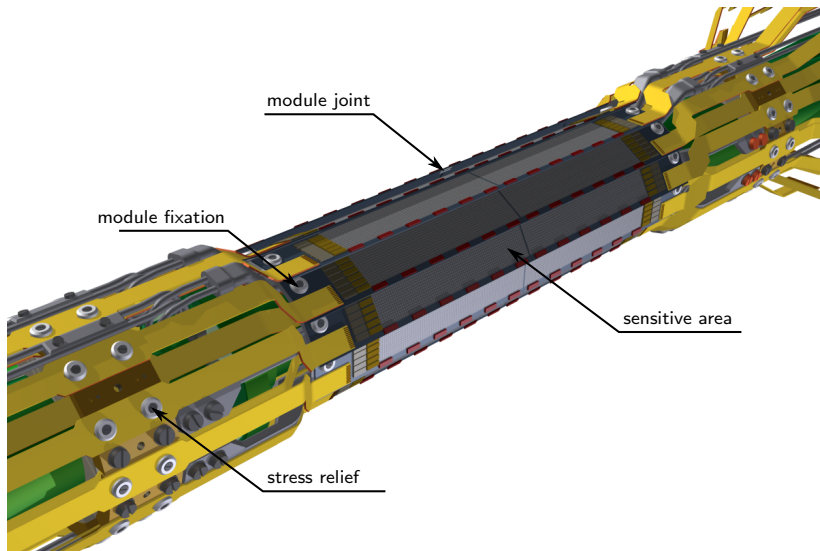
PXD Support

Inner layer and carbon tubes



PXD Support

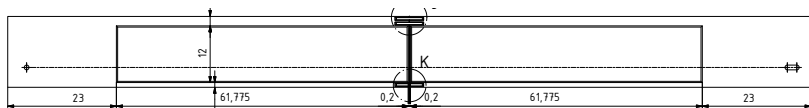
Complete PXD



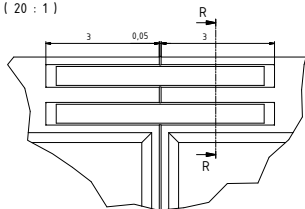
PXD Mockup



Module Glueing



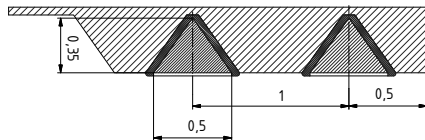
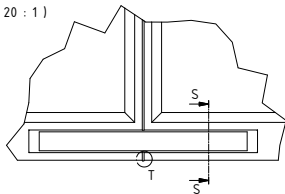
J (20 : 1)



Reinforced front face glueing

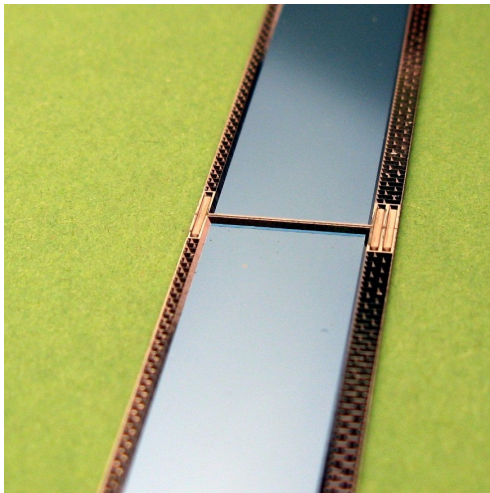
- ▶ reinforced using ceramic “prisms”
- ▶ almost no additional material
- ▶ only $\sim 500 \mu\text{m}$ of dead area

K (20 : 1)

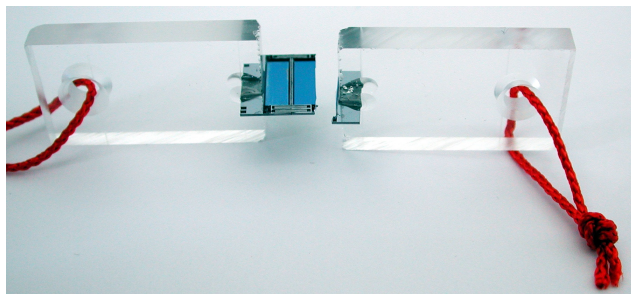
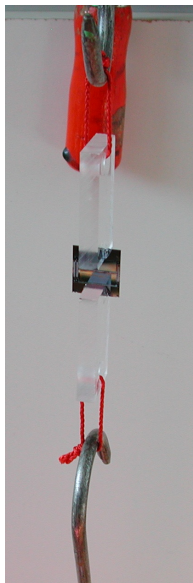


Test Glueing

Test glueing of mechanical dummies thinned to $50\ \mu\text{m}$ to verify design



Tensile Strength Test



Tensile strength test carried out:

- ▶ ends of the module fixated
- ▶ increasing force applied to pull the pieces apart
- ▶ solid 450 μm silicon tested to 7 kg
- ▶ unthinned front face glueing achieved ~ 6 kg

Long time test (unthinned, 3 kg) still ongoing: 6 weeks already achieved



Strength Test Results

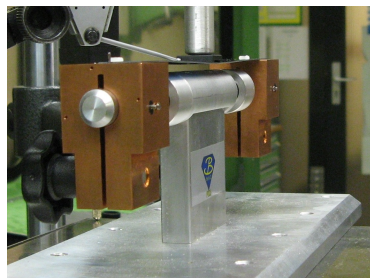
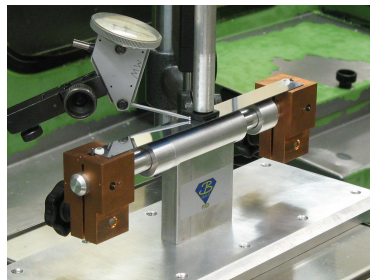
- ▶ module broke just above 5 kg
- ▶ glue more or less still intact
- ➔ silicon seems to be weaker then glue (for 50 μm)
- ▶ long time test with 3 kg broke after few hours: silicon again the weak part



Bowing Strength Test

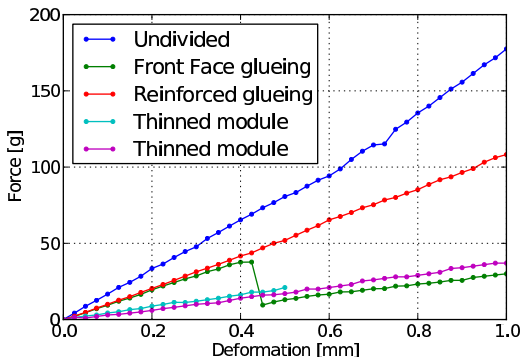
Additional test to study deformation perpendicular to module axis

- ▶ module screwed to endplate on both sides
- ▶ one endplate fixed, one free to slide along module axis
- ▶ applying pressure to module center (0.025 mm every 15 seconds) up to 1 mm deformation



Bowing Test Results

- ▶ undivided, inner layer dummy broke at deformation of 1.445 mm (equivalent to a force of 315 g)
 - ▶ front face glued outer layer module:
 - ▶ glueing broke at 0.4 mm deformation (37.7 g)
 - ▶ half modules remained in good order, tested to 1 mm deformation (~ 30 g)
 - ▶ reinforced glueing successfully tested up to 1 mm deformation (110 g)
-
- ▶ thinned down outer layer dummy tested up to 1 mm deformation (35 g)
 - ▶ cracks in thinned area: no growing visible

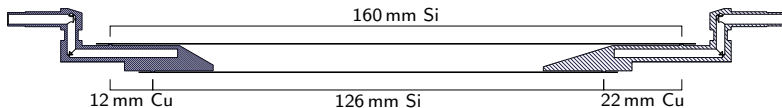


Thermal Mechanical Tests

Goal: Verify Mechanical Design

Baseline: Modules screwed to endflange to ensure good thermal contact and positional stability

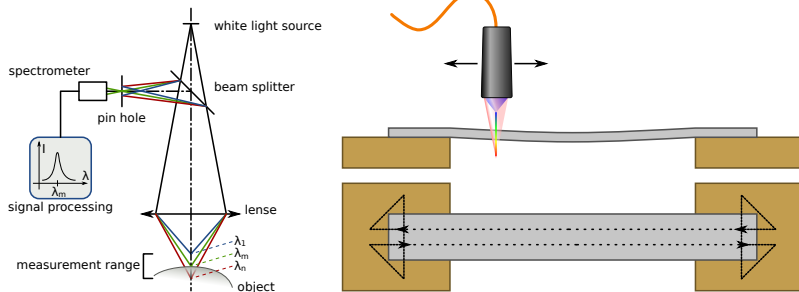
One Issue: Internal stress due to thermal expansion



- ➔ Difference between thermal expansion of inner and outer layer $\sim 20 \mu\text{m}$ for $\Delta T = 40^\circ\text{C}$
- ➔ we need to make sure that modules and glue remain stable over the whole temperature range

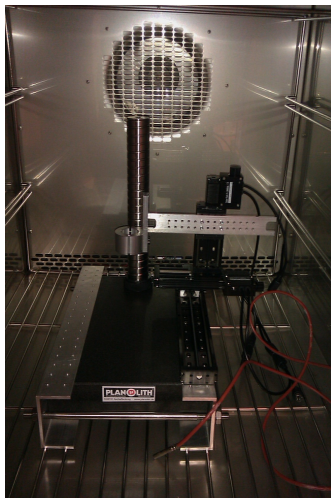
Precise position/distance measurement over “large” temperature range needed.

Confocal Chromatic Distance Sensor



- ▶ high resolution ($\sim 1 \mu\text{m}$ axial, $\sim 10 \mu\text{m}$ lateral)
- ▶ contact free measurement
- ▶ almost independent of material (max. slope depends on reflectivity)
- ▶ passive sensor: large temperature range possible
- ▶ high measurement rate up to 2 kHz

The Setup



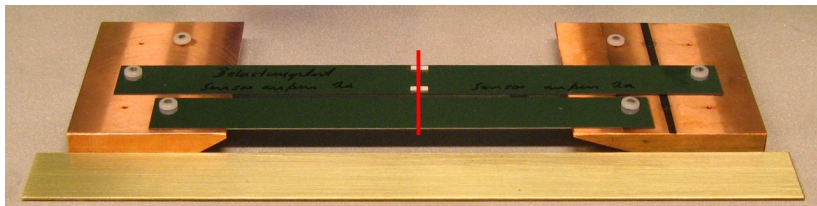
We have prepared a setup to profile modules during temperature cycling

- ▶ granite reference plane with $\pm 2 \mu\text{m}$ planarity
- ▶ range of $200 \text{ mm} \times 50 \text{ mm}$ in XY-Plane, $< 2 \mu\text{m}$ repeatability
- ▶ Z-range of 3 mm, resolution of $< 1 \mu\text{m}$
- ▶ possibility to adjust Z-position by 50 mm
- ▶ temperature Range from 0°C to 50°C

But: No Results Yet

- ▶ still calibrating
- ▶ technical problems with climate chamber

First tests



Obtained test system to check performance.

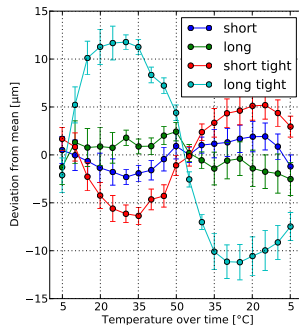
But: only measurement in one direction

- ▶ measured height of module surface
- ▶ covered $\Delta T = 45^\circ\text{C}$
- ▶ first results: most changes are from movement of the stage
- ▶ no significant movement after preliminary calibration



additional run with tightened screws

- ▶ movement visible, but not yet understood
- ▶ silicon damaged due to high torque



Conclusions

Belle II will be major upgrade to Belle

- ▶ Vertex finding is paramount for CP Violation measurements
- ▶ low material budget for vertex detector required due to low momenta

The DEPFET Pixel Vertex Detector can satisfy all requirements

- ▶ small size allows to keep support out of acceptance
- ▶ silicon as “self supporting structure”
- ▶ tests needed to verify feasibility
- ▶ so far very promising results



CP Violation

- ▶ CP violated in weak interactions
- ▶ represented by non-vanishing complex phase in the weak mixing matrix (CKM model, Nobel Prize 2008 for Kobayashi & Maskawa)

$$\begin{pmatrix} |d'\rangle \\ |s'\rangle \\ |b'\rangle \end{pmatrix} = \underbrace{\begin{pmatrix} V_{ud} & V_{us} & V_{ub} \\ V_{cd} & V_{cs} & V_{cb} \\ V_{td} & V_{ts} & V_{tb} \end{pmatrix}}_{C_{CKM}} \begin{pmatrix} |d\rangle \\ |s\rangle \\ |b\rangle \end{pmatrix}$$

Precision Measurement of CP-Violation

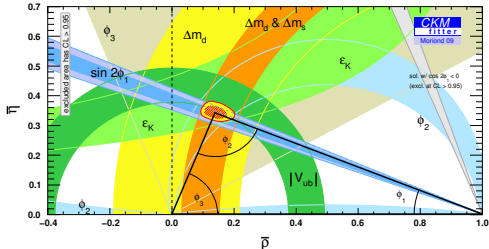
- ▶ verification of the CKM model
- ▶ search for new sources of CP Violation → New Physics
- ▶ B mesons show large CP-Violation, well suited for CP measurements
- ▶ high statistics and precision needed to challenge SM

Unitarity Triangle

- ▶ unitarity of CKM matrix leads to column constraints $\sum_k V_{ik} V_{jk}^* = 0$
- ▶ triangles in complex space
- ▶ almost degenerate in Kaon system, large angles in B meson system

$$V_{ud} V_{ub}^* + V_{cd} V_{cb}^* + V_{td} V_{tb}^* = 0$$

$\mathcal{O}(\lambda^3)$ $\mathcal{O}(\lambda^3)$ $\mathcal{O}(\lambda^3)$



$$\bar{\rho} = \left(1 - \frac{\lambda^2}{2}\right) \rho \quad \bar{\eta} = \left(1 - \frac{\lambda^2}{2}\right) \eta$$

$$\phi_1 = \arg\left(-\frac{V_{cd} V_{cb}^*}{V_{td} V_{tb}^*}\right) \quad \phi_2 = \arg\left(-\frac{V_{td} V_{tb}^*}{V_{ud} V_{ub}^*}\right)$$

$$\phi_3 = \arg\left(-\frac{V_{ud} V_{ub}^*}{V_{cd} V_{cb}^*}\right)$$

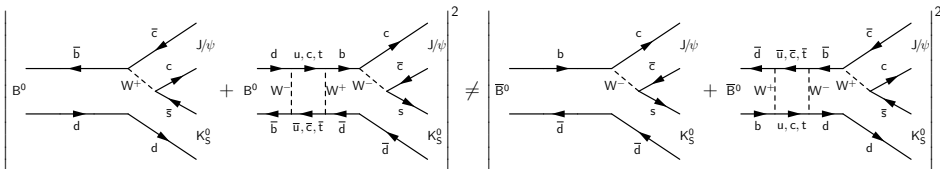
CP Observables

time dependent decay asymmetry

$$a_{CP}(t) = \frac{\Gamma(\bar{B}^0 \rightarrow f_{CP}; t) - \Gamma(B^0 \rightarrow f_{CP}; t)}{\Gamma(\bar{B}^0 \rightarrow f_{CP}; t) + \Gamma(B^0 \rightarrow f_{CP}; t)}$$

3 possible contributions

- ▶ CP-Violation in decay (direct)
- ▶ CP-Violation in mixing (indirect)
- ▶ CP-Violation by interference of mixing and decay (mixing induced)



For B mesons, contributions from indirect CP-Violation are negligible

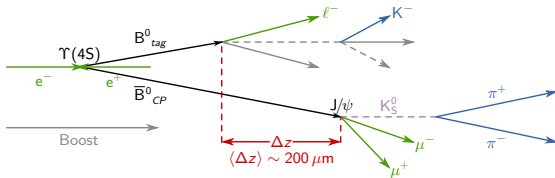
Measurement of CP-Violation

time dependent decay asymmetry

$$a_{CP}(t) = \frac{\Gamma(\bar{B}^0 \rightarrow f_{CP}; t) - \Gamma(B^0 \rightarrow f_{CP}; t)}{\Gamma(\bar{B}^0 \rightarrow f_{CP}; t) + \Gamma(B^0 \rightarrow f_{CP}; t)}$$

Experimental challenging

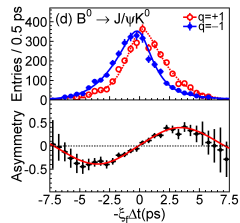
- ▶ lifetime of B mesons is 1.5 ps
- ▶ flavour of B meson has to be known



Solution

- ▶ $\Upsilon(4S)$: coherent B-meson pair production
- ▶ one B to determine flavour (tag side), other B for CP measurement (CP side)
- ▶ boost system using asymmetric beam energies

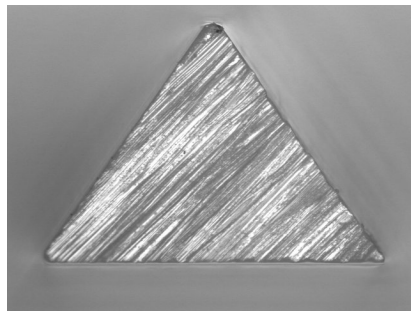
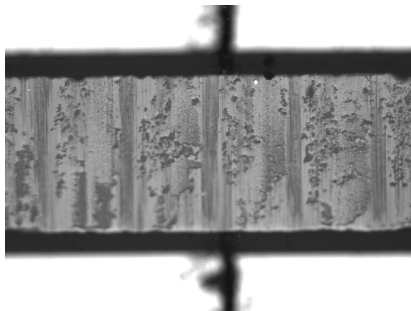
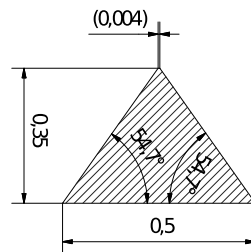
$$t \rightarrow \Delta t = \frac{\Delta z}{\langle \beta \gamma \rangle c}$$



Ceramic Reinforcements

Initial batch of ceramic reinforcements received

- ▶ fitting very well into grooves
- ▶ manufactured within $42\ \mu\text{m}$ to specification



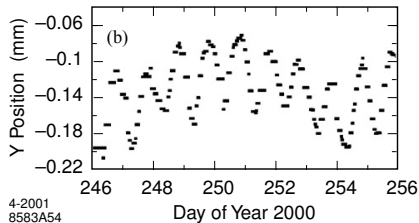
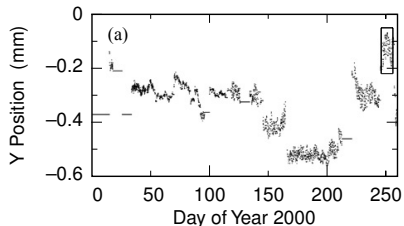
Alignment

Required spatial resolution: $\approx 10 \mu\text{m}$

PXD + SVD

- ▶ pixel-detector mounted directly on the beampipe
- ▶ double-sided strip-detector attached to the CDC
- ▶ mechanically independent subsystems
- ▶ frequent and large relative movements possible

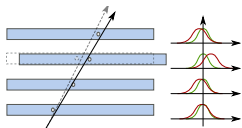
➔ frequent, time-dependent alignment needed



Global alignment of the BABAR SVT

Track-based Alignment

- ▶ \mathbf{a} = alignment parameters
- ▶ $\boldsymbol{\tau}$ = track parameters



$$\chi^2(\mathbf{a}, \boldsymbol{\tau}) = \boldsymbol{\epsilon}(\mathbf{a}, \boldsymbol{\tau})^T \mathbf{V}^{-1} \boldsymbol{\epsilon}(\mathbf{a}, \boldsymbol{\tau})$$

$$\chi^2(\mathbf{a}, \boldsymbol{\tau}) = \sum_{i \in \text{tracks}} \sum_{j \in \text{hits}} \left(\frac{\text{track}(\mathbf{a}, \boldsymbol{\tau}_i) - \text{hit}_j}{\sigma_j} \right)^2$$

Solution for linearized χ^2

$$\underbrace{(\mathbf{J}^T \mathbf{V}^{-1} \mathbf{J})}_{\mathbf{c}} \begin{pmatrix} \Delta \mathbf{a} \\ \delta \boldsymbol{\tau} \end{pmatrix} = \underbrace{(\mathbf{J}^T \mathbf{V}^{-1} \boldsymbol{\epsilon}(\mathbf{a}_0, \boldsymbol{\tau}_0))}_{\mathbf{b}}$$

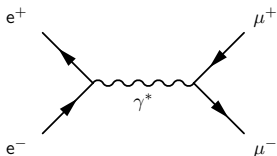
local alignment:

- ▶ neglect correlations between modules
- ▶ keep track parameters fixed
- ▶ χ^2 -function per module
- ▶ small matrices (6×6)
- ▶ iteration needed to account for correlations

global alignment (Millepede):

- ▶ one global χ^2 -function
- ▶ all correlations taken into account
- ▶ “large” set of equations (1476×1476 for Belle, similar for Belle II)
- ▶ widely used program package available

Alignment with $e^+e^- \rightarrow \mu^-\mu^+$



Goal

Implementation of a new alignment procedure for the Belle SVD2 using mainly muon pairs from e^+e^- annihilation as preparation for Belle II

- ▶ high statistics

$$\begin{aligned}\sigma(e^+e^- \rightarrow \mu^+\mu^-) &\approx 0.77 \text{ nb} \\ &\sim 15 \text{ s}^{-1} @ 2 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1} \\ &\sim 600 \text{ s}^{-1} @ 8 \times 10^{35} \text{ cm}^{-2}\text{s}^{-1}\end{aligned}$$

- ▶ large transverse momentum
 $p_t \gtrsim 2 \text{ GeV}$
 - ▶ back to back in center of mass system
 - ▶ **not** back to back in Lab system
(asymmetric energies, crossing angle)
- ➡ fit tracks on same vertex, constraining energy and momentum to boost 4-vector.

